

Title (en)

MICROWAVE-ASSISTED APPARATUS, SYSTEM AND METHOD FOR DEPOSITION OF FILMS ON SUBSTRATES

Title (de)

MIKROWELLENUNTERSTÜTZTE VORRICHTUNG, SYSTEM UND VERFAHREN ZUR ABSCHIEDUNG VON FILMEN AUF SUBSTRATEN

Title (fr)

APPAREIL ASSISTÉ PAR MICRO-ONDES, SYSTÈME ET PROCÉDÉ DE DÉPÔT DE FILMS SUR SUBSTRATS

Publication

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Application

EP 20883017 A 20201102

Priority

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Abstract (en)

[origin: WO2021084561A1] The present invention provides an apparatus for the deposition of thin films on a substrate, including large substrates, held preferably face-down, in a cartridge containing a liquid solution with at least a chemical precursor which, upon being subject to a uniform microwave field transmitted through a microwave-transparent window, leads to the formation of a thin film on the substrate. The present invention also provides a system for launching microwaves and controlling the process for film deposition on the substrate. The present invention also provides a process for obtaining a film of uniform thickness and characteristics on a substrate or for incorporating controlled non-uniformity. The present invention also provides an apparatus and method for film deposition on a series of substrates in a continuous batch process.

IPC 8 full level

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Citation (search report)

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- See references of WO 2021084561A1

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